

L Number	Hits	Search Text	DB	Time stamp
1	3371	((mems or microelectromechanical or (micro adj electro adj mechanical)) and (torsion or rotat\$3))	USPAT; US-PGPUB; EPO; JPO; DERWENT; IBM_TDB	2003/10/20 17:14
2	2503	((mems or microelectromechanical or (micro adj electro adj mechanical)) and (torsion or rotat\$3)) and substrate\$1	USPAT; US-PGPUB; EPO; JPO; DERWENT; IBM_TDB	2003/10/20 17:14
3	1677	((((mems or microelectromechanical or (micro adj electro adj mechanical)) and (torsion or rotat\$3)) and substrate\$1) and voltage\$1	USPAT; US-PGPUB; EPO; JPO; DERWENT; IBM_TDB	2003/10/20 17:12
4	529	((mems or microelectromechanical or (micro adj electro adj mechanical)) and (torsion))	USPAT; US-PGPUB; EPO; JPO; DERWENT; IBM_TDB	2003/10/20 17:14
5	437	((mems or microelectromechanical or (micro adj electro adj mechanical)) and (torsion)) and substrate\$1	USPAT; US-PGPUB; EPO; JPO; DERWENT; IBM_TDB	2003/10/20 17:14
6	303	((((mems or microelectromechanical or (micro adj electro adj mechanical)) and (torsion)) and substrate\$1) and (electrode\$1 and voltage\$1)	USPAT; US-PGPUB; EPO; JPO; DERWENT; IBM_TDB	2003/10/20 17:17
7	245	(((((mems or microelectromechanical or (micro adj electro adj mechanical)) and (torsion)) and substrate\$1) and (electrode\$1 and voltage\$1)) and switch\$3	USPAT; US-PGPUB; EPO; JPO; DERWENT; IBM_TDB	2003/10/20 17:24
8	195	(((((mems or microelectromechanical or (micro adj electro adj mechanical)) and (torsion)) and substrate\$1) and (electrode\$1 and voltage\$1)) and switch\$3) and array	USPAT; US-PGPUB; EPO; JPO; DERWENT; IBM_TDB	2003/10/20 17:24